

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. : 10/579,777 Confirmation No. : 5716
First Named Inventor : Hiraku ISHIKAWA
Filed : February 26, 2008
TC/A.U. : 1792
Examiner : Shamim Ahmed

Docket No. : 101994.57726US
Customer No. : 23911

Title : Plasma Film-Forming Apparatus and Plasma Film-Forming Method

REPLY TO OFFICE ACTION

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

The following remarks are respectfully submitted in response to the final Office Action dated April 21, 2009.

The **Listing of Claims** begins on page 2 of this paper.

Remarks begin on page 5 of this paper.